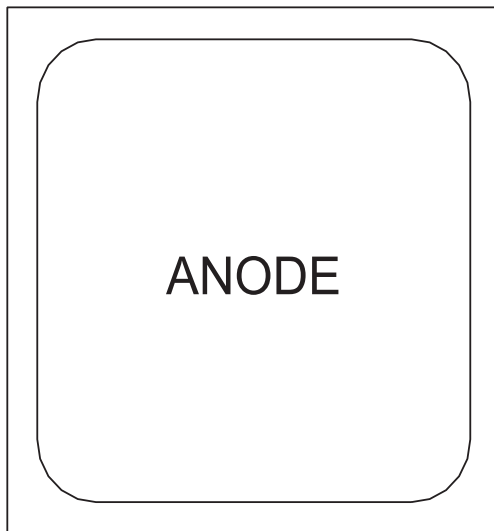


PROCESS DETAILS

| | |
|------------------------|-----------------------|
| Process | GLASS PASSIVATED MESA |
| Die Size | 50 x 50 MILS |
| Die Thickness | 12.2 MILS |
| Anode Bonding Pad Area | 34 x 34 MILS |
| Top Side Metalization | Au - 5,000Å |
| Back Side Metalization | Au - 2,000Å |

GEOMETRY



BACKSIDE CATHODE

R0

GROSS DIE PER 4 INCH WAFER

4,520

PRINCIPAL DEVICE TYPES

UES1001 thru UES1003

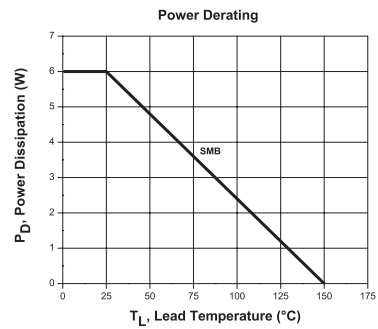
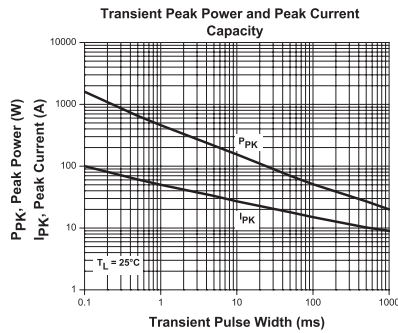
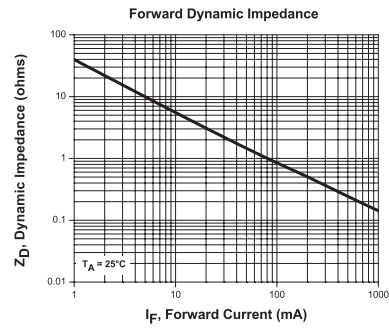
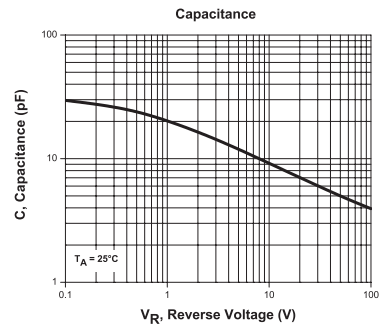
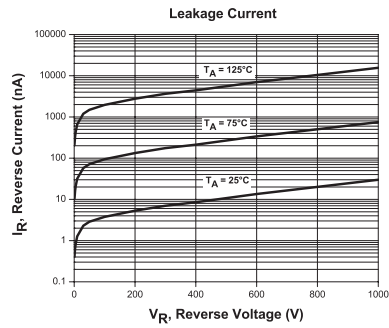
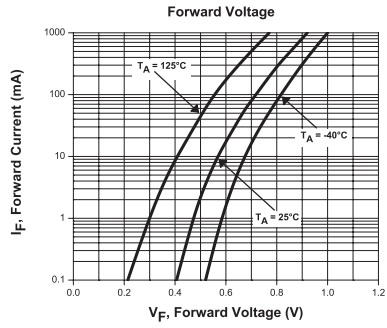
UF4001 thru UF4007

CMR1U-01 Series

CMR1U-01M Series

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R3 (24-August 2006)



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